

MSE-659

Introduction to scanning electron microscopy microanalysis techniques

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Cursus	Sem.	Type
Materials Science and Engineering		Opt.

Language of teaching	English
Credits	1
Session	
Exam	Written
Workload	30h
Hours	18
Courses	15
TP	3
Number of positions	

Frequency

Every 2 years

Remark

Course canceled

Summary

Modern Scanning Electron Microscopes, when combined with focused ion beams (Dual beam FIBs), provide a larger number of multimodal imaging and different analytical methods. The course format consists of introductory lectures, lectures on advanced techniques and practical work.

Content

Please find information on the link : <https://www.epfl.ch/research/domains/ccmx/courses-and-events/sem2019/>

Keywords

Scanning Electron Microscopy; microanalysis, multimodal imaging, analytical methods, chemical analysis.

Resources

Websites

- <https://www.epfl.ch/research/domains/ccmx/courses-and-events/sem2019/>